



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Das et al.

Serial No.: 10/045,542

Filed: October 26, 2001

Confirmation No.: 3570 Group Art Unit: 1762 Examiner: Michael. E. Barr

METHOD OF FABRICATING AN OXIDE LAYER ON A SILICON CARBIDE

LAYER UTILIZING AN ANNEAL IN A HYDROGEN ENVIRONMENT

Date: February 20, 2003

Commissioner for Patents Washington, DC 20231



AMENDMENT

Sir:

Applicants provide the present Amendment to address the issues raised in the Official Action mailed November 21, 2002. Applicants provide the present Amendment pursuant to the Revised Amendment Format instituted for the prototype Electronic File Wrapper program described in 1265 Off. Gaz. Pat. Office 87 (Dec. 17, 2002) and that has been expanded to include all Technology Centers and amendments to the specification and drawings. Thus, the provisions of 37 C.F.R. 1.121(a), (b), (c) and (d) are waived for the present Amendment.